

Written Examination EITP25

June 4th 2020

Useful constants:

$$\hbar = 1.055 \times 10^{-34} \text{ Js}$$

$$k_B = 1.381 \times 10^{-23} \text{ J/K}$$

$$m_0 = 9.109 \times 10^{-31} \text{ kg}$$

$$\epsilon_0 = 8.85 \times 10^{-12} \text{ Fm}^{-1}$$

$$e = q = 1.602 \times 10^{-19} \text{ C}$$

$$c = 2.998 \times 10^8 \text{ m/s}$$

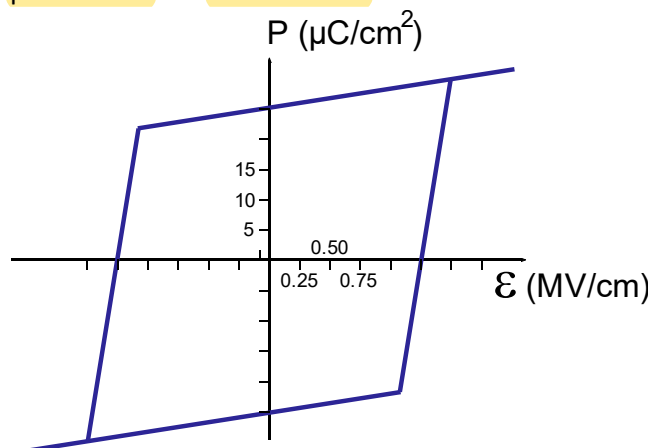
Solve the Five tasks below. Maximum score is 60p.

1. Spiking Neural Networks (SNN) (12p)

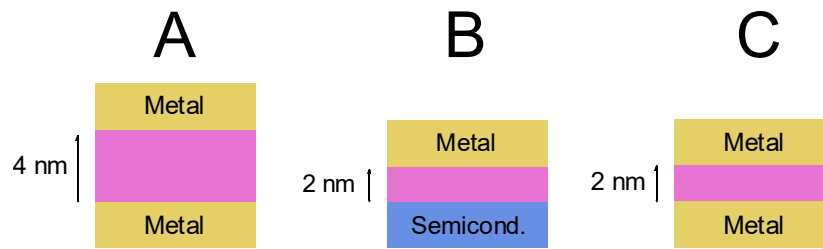
- Explain what makes an SNN so much more energy efficient compared to a regular artificial neural network.
- What is Spike-Time-Dependent Plasticity (STDP) and how does one implement it in an memristor-based SNN?
- Explain how STDP achieves stable neuron output activity level given an excessive and random input activity.

2. Ferroelectric devices (12p)

- In the following diagram measured on a FERAM device extract the remanent polarisation and coercive field.



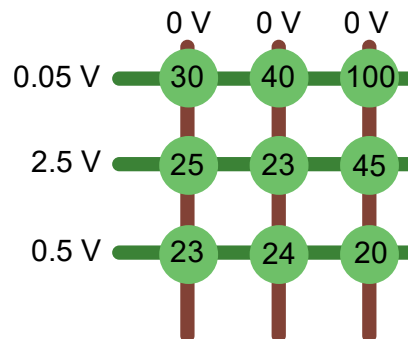
- b. Rank the following FTJ devices in terms of their **resistance contrast** ($R_{\text{high}}/R_{\text{low}}$):



- c. Given a FeFET with a 10 nm HfZrO_2 ferroelectric gate oxide ($\epsilon_r = 20$) and $\epsilon_c = 1.5 \text{ MV/cm}$. Defects at the interface to the semiconductor results in a series capacitance of $5 \mu\text{F/cm}^2$. Using the following expression for the **depolarisation field**
- $$E_{\text{dep}} = -P \left[\epsilon_0 \epsilon_r \left(\frac{C_{\text{series}}}{C_{\text{FE}}} + 1 \right) \right]^{-1}$$
- calculate the **remanent polarisation** in the device.

3. ReRAM and MRAM (12p)

- a. An 8-bit ReRAM memristor array is programmed to the following conductance values and word line voltages (bit lines are grounded):



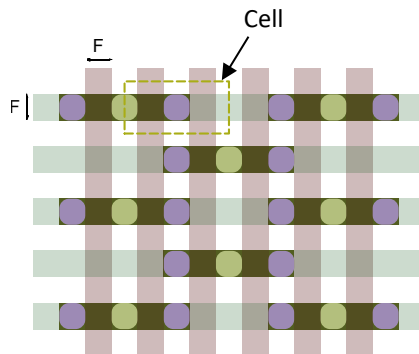
What will the current on each bit line be, and what **linear matrix equation** does this situation map to? What is the solution to the equation?

- b. Describe what happens on a microscopic scale during FORMING, SET and RESET operations in a ReRAM device based on **valence-change**.
- c. Name and explain the **three key physical mechanisms** that has enabled MRAM as a viable technology?

4. Integration (12p)

- a. Given a **large memory array**, if the device furthest from the WL bias source is selected, name and explain two potential issues and how to solve them.
- b. What are the important characteristics of **selector devices** to be used for an array of PCM or FeFET memory cells, respectively? Explain why.

- c. Assume a DRAM technology with where each DRAM cell looks like this with $F = 30$ nm:



Assuming a **chip size** of 50 mm^2 and **area efficiency** of 50%, how high memory capacity does the chip have?

5. Neuromorphic technology (12p)

- a. Rank the following **non-idealities** of a memristor device in terms of their negative influence of the **training performance** of a SNN (worst comes first):
 1. Non-linear potentiation/depression
 2. Asymmetric potentiation/depression
 3. Cycle-to-cycle pot./dep. Variation
 4. Dynamic range
- b. Using a 2-PCM device one can achieve a **negative synaptic weight**. How do you operate such a device considering that SET can be gradual but RESET is abrupt for PCM?
- c. Draw a circuit that implements a **Leaky Integrate-and-Fire** Neuron.

Good Luck!